

BS EN 62047-13:2012



BSI Standards Publication

# Semiconductor devices — Micro-electromechanical devices

Part 13: Bend- and shear- type test methods  
of measuring adhesive strength for MEMS  
structures

**National foreword**

This British Standard is the UK implementation of EN 62047-13:2012. It is identical to IEC 62047-13:2012.

The UK participation in its preparation was entrusted to Technical Committee EPL/47, Semiconductors.

A list of organizations represented on this committee can be obtained on request to its secretary.

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